

INFORMATION DISCLOSURE CITATION IN AN APPLICATION (Use several sheets if necessary) PTO Form 1449	Atty Docket No. 113197-020	Application No. Unknown
	Applicant Yamamoto, S., et al.	
	Filing Date January 14, 2002	Group Unknown



U.S. PATENT DOCUMENTS							
Examiner's Initials		Document Number	Publication Date	Inventor	Class	Subclass	Filing Date If Appropriate
MAH		3,993,939	11-23-76	Slavin et al.			
MAH		4,092,696	5-30-78	Boesen et al.			
MAH		4,823,230	4-18-89	Tiemann			
MAH		4,831,492	5-16-89	Kuisma			
MAH		4,838,088	6-13-89	Murakami			
MAH		5,186,054	2-16-93	Sekimura			
MAH		5,241,864	9-7-93	Addie et al.			
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MAH		6,109,113	8-29-00	Chavan et al.			

FOREIGN PATENT DOCUMENTS							
Examiner's Initials		Document Number	Publication Date	Country	Class	Subclass	Translation Yes No
MAH		11-326095	11-26-99	Japan			

Examiner's Initials		OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)
MAH		Seidel, H., et al., "Anisotropic Etching of Crystalline Silicon in Alkaline Solutions," J. Electrochem. Soc., Vol. 137, No. 11, November 1990, pp. 3626-3632.

Examiner: <i>Marcia Jeger</i>	Date Considered: <i>10/1/02</i>
*Examiner: Initial if citation considered, whether or not citation is in conformance with PEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	